

Fig. 4-16 SEM micrographs of CW laser crystallized poly-silicon films after Secco etching for 60sec treatment. The constant laser power is 4W. The scan speed is 6cm/sec, the grain size of area “a” is larger than 3um

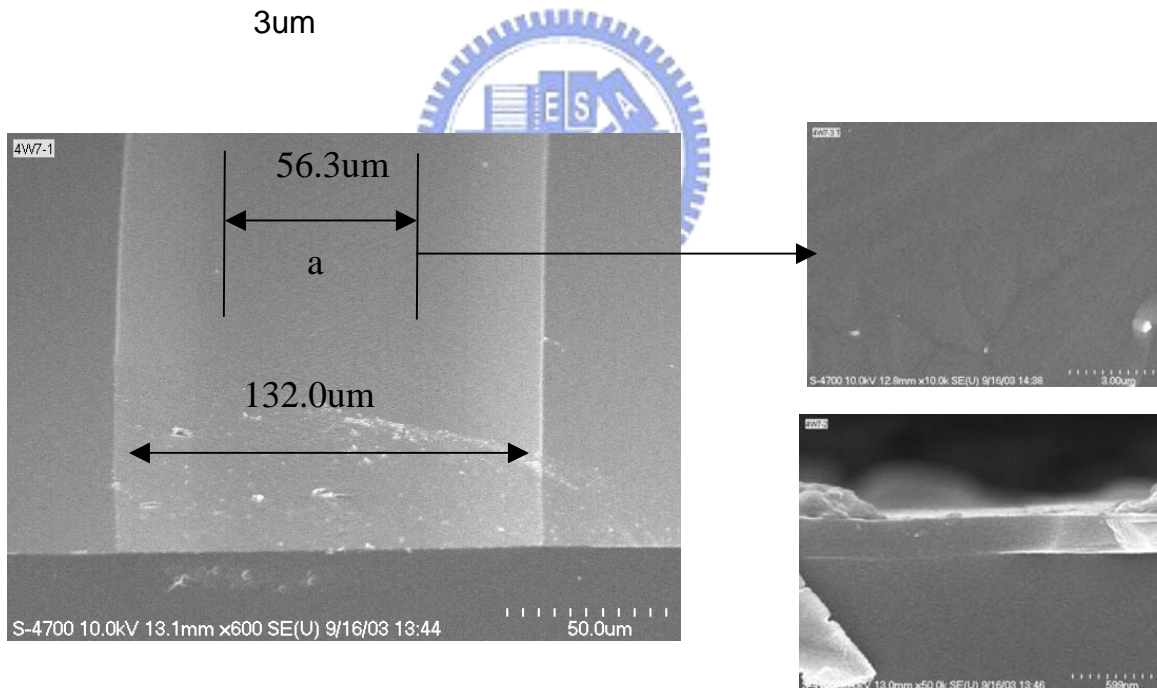


Fig. 4-17 SEM micrographs of CW laser crystallized poly-silicon films after Secco etching for 60sec treatment. The constant laser power is 4W. The scan speed is 7 cm/sec, the grain size of area “a” is larger than 3um